

**OPTICAL CHARACTERIZATION
TECHNIQUES CONFERENCE
ANNOUNCEMENT**

The Society of Photo-Optical Instrumentation Engineers (SPIE), for which the Materials Research Society is a cooperating organization, has announced a conference on Optical Characterization Techniques for Semiconductor Technology to be held April 1-2, 1981 at the San Jose Hyatt House, San Jose, California. This technical conference will be devoted to optical characterization techniques with special emphasis on process control and examining and monitoring bulk materials, thin films, surfaces and interfaces. Applications and recent developments will be discussed through tutorials and contributed papers.

Selection of papers will be based on abstracts limited to 200-300 words. The abstract deadline is November 24, 1980. Further information regarding suitable topics, abstracts and manuscript requirements may be obtained by contacting the Seminar Chairman, D. E. Aspnes of Bell Laboratories, Murray Hill, New Jersey 07974.

Suggestions and comments relevant to the format and content of this Newsletter are welcomed, and may be sent to:

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